Small-scale materials and nanostructures are attracting considerable worldwide research interest due to their potential applications. Even though small-scale materials are paramount for their respective applications, an understanding of the mechanical properties of such small volumes of materials is far from clear due to the lack of an appropriate test technique that is quantitative at such small scales. To accommodate this need for testing mechanical properties of materials at nanoscale, Bruker offers the Push-to-Pull (PTP) Device, an in-situ tensile apparatus designed to work seamlessly with Hysitron® PI Series PicoIndenters for TEM and SEM.

The PTP apparatus not only enables quantitative tensile load-displacement data simultaneously with real-time imaging of the microstructure behavior, it also simplifies the sample preparation procedure, and serves as an energy buffer, strain sensor, and force calibration.

**Push-to-Pull Device Features**
- Quantitative tensile load-displacement data simultaneously acquired with real-time imaging of the microstructural behavior
- Device portability for easy transfer between FIB and SEM/TEM
- Easy insert in commercially available Hysitron PI Series PicoIndenters for in-situ tensile testing
- Consumable, multi-use MEMS-fabricated apparatus
- Single device compatibility with both SEM and TEM Hysitron PicoIndenter instruments
- Three different stiffness values (15, 150, and 450 N/m) available for use with a variety of materials and sizes
Example Application:
Mechanical Properties of One Dimensional ZnO Nanostructures

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Acknowledgements:
The quantitative in-situ TEM tensile research was supported, in whole or in part, by a DOE Phase II SBIR grant (DE-FG02-07ER84813) awarded to Hysitron, Inc. This work was performed at NCEM, LBL, which is supported by the office of Science, Office of Basic Energy Sciences of the U.S. Department of Energy under Contract No. DE-AC02-05CH11231.